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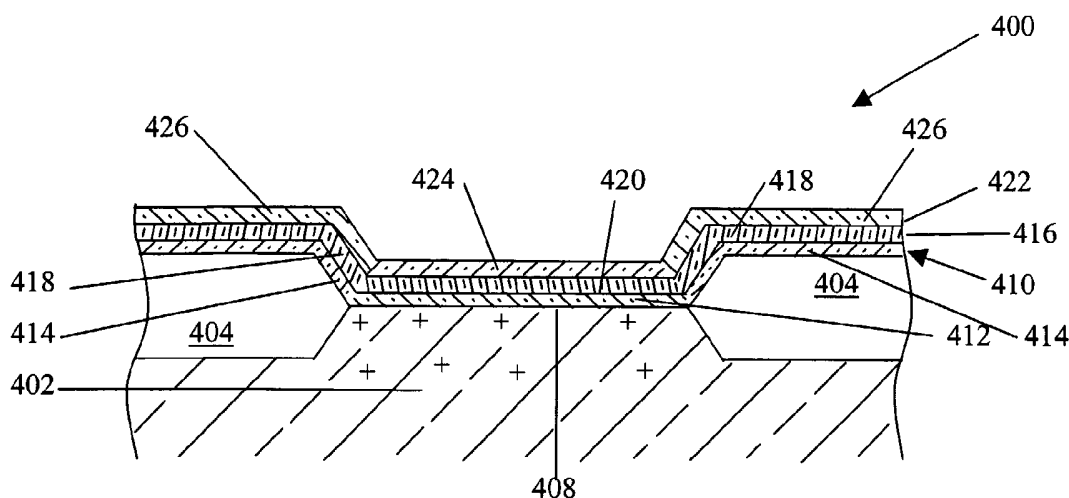
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- (71) Applicant: **ASM AMERICA, INC.** [US/US]; 3440 East University Drive, Phoenix, AZ 85034-7200 (US).
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(54) Title: DEPOSITION METHOD OVER MIXED SUBSTRATES USING TRISILANE



(57) Abstract: Trisilane is used in chemical vapor deposition methods to deposit silicon-containing films over mixed substrates. Such methods are useful in semiconductor manufacturing to provide a variety of advantages, including uniform deposition over heterogeneous surfaces, high deposition rates, and higher manufacturing productivity. An example is in forming the base region of a heterojunction bipolar transistor, including simultaneous deposition over both single crystal semiconductor surfaces and amorphous insulating regions.

## INTERNATIONAL SEARCH REPORT

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A. CLASSIFICATION OF SUBJECT MATTER  
IPC 7 H01L21/205 C23C16/00

According to International Patent Classification (IPC) or to both national classification and IPC

## B. FIELDS SEARCHED

Minimum documentation searched (classification system followed by classification symbols)

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Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched

Electronic data base consulted during the international search (name of data base and, where practical, search terms used)

EPO-Internal, PAJ, WPI Data, INSPEC

## C. DOCUMENTS CONSIDERED TO BE RELEVANT

Category *	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
X	EP 0 368 651 A (FUJITSU LTD) 16 May 1990 (1990-05-16)  column 10, line 1 - line 49; claims 1-5,8; figure 3; examples 1,3,4,7,C	1-9, 12-27, 29-31, 33-35
Y	---	10,11,32
X	EP 0 486 047 A (SEIKO EPSON CORP) 20 May 1992 (1992-05-20)  column 5, line 32 -column 9, line 15; figures 1A,1B  --- -/--	1,6-9, 12-16, 19-22, 25-27, 30,31



Further documents are listed in the continuation of box C.



Patent family members are listed in annex.

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- \*&\* document member of the same patent family

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## C.(Continuation) DOCUMENTS CONSIDERED TO BE RELEVANT

Category °	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
Y	PATENT ABSTRACTS OF JAPAN vol. 017, no. 375 (E-1397), 14 July 1993 (1993-07-14) & JP 05 062911 A (FUJITSU LTD), 12 March 1993 (1993-03-12) abstract	10,11,32
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